

METHOD OF USING AN ADHESION PRECURSOR

FIG. 1

METHOD OF USING AN ADHESION PRECURSOR LAYER FOR CHEMICAL VAPOR DEPOSITION (CVD) COPPER DEPOSITION (LOPATIN, ET AL.) Atty. Docket No.: 039153-0484 Attorney: Paul S. Hunter (608) 258-4292

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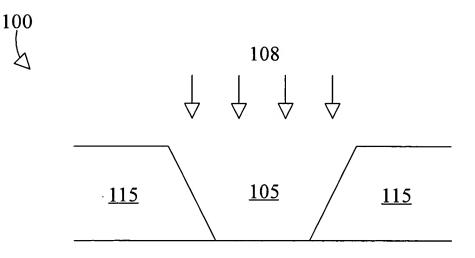


FIG. 2

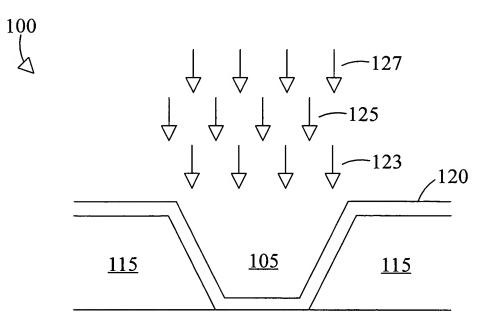
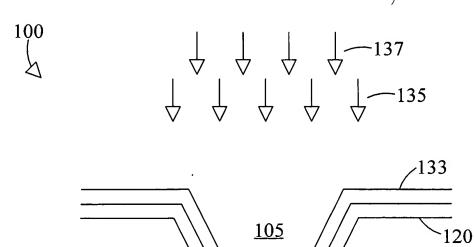


FIG. 3

METHOD OF USING AN ADHESION PRECURSOR LAYER FOR CHEMICAL VAPOR DEPOSITION (CVD) COPPER DEPOSITION (LOPATIN, ET AL.) Atty. Docket No.: 039153-0484

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FIG. 4

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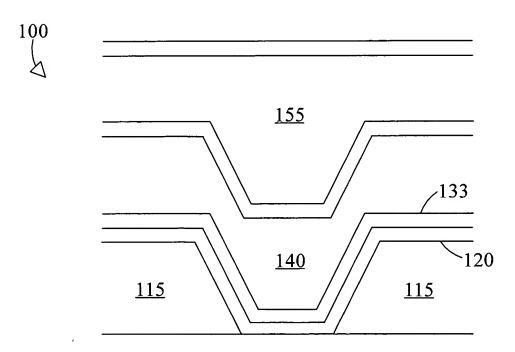


FIG. 5